## 2 FEBOL 2 FEBOL P. Tallut IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Joseph S. HAYDEN et al.

Serial No.:

09/492,178

Filed:

For:

January 27, 2000

IMPROVED ION EXCHANGE TECHNOLOGY FOR FABRICATION OF WAVEGUIDE SOURCE LASERS

Examiner: Unassigned

Group Art Unit: 2874

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents Washington, DC 20231

TECHNOLOGY CENTER 2800

Sir:

This Information Disclosure Statement is being submitted in connection with Applicants' continuing duty of disclosure under 37 C.F.R. §1.56.

This statement is being filed before the mailing date of the first office action on the merits in accordance with 37 C.F.R. §1.97(b) and, thus, no fee is required herein.

## **Listing of the References**

See the attached form PTO-1449. Copies of the cited documents are attached.

## **Explanation of the Relevancy of the Cited Disclosures**

All of the cited references are in the English language in accordance with 37 C.F.R. §1.98.

Respectfully submitted,

By:

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